## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| Applicant: Hiroyuki KANBARA et al.   |                   |
|--|-------------------|
| Application No.: 10/596,000  | Art Unit: 1722    |
| Confirmation No.: 1561   |                   |
| Filing or 371(c) Date: January 17, 2007  | Examiner: A. Eoff |
| Title: METHOD FOR FORMING THICK FILM PATTERN, METHOD FOR MANUFACTURING ELECTRONIC COMPONENT, AND PHOTOLITHOGRAPHY PHOTOSENSITIVE PASTE |                   |
| AMENDMENT Commissioner for Patents P.O. Box 1450   |                   |
| 1.0.00   |                   |

Alexandria, VA 22313-1450

Sir:

| In response to the Office Action dated March 11, 2011, the period for response to    |
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| which has been extended to September 12, 2011 (September 11, 2011 falls on a         |
| Sunday), by the accompanying Petition for Three-Month Extension of Time, please      |
| amend the above-identified application as follows:                                   |
| Amendments to the Specification begin on page of this paper.                         |
| Amendments to the Claims are reflected in the listing of the claims which            |
| begins on page 2 of this paper.  |
| ☐ Amendments to the Drawings begin on page of this paper and include an              |
| attached replacement sheet. An Appendix including the amended drawing figures is     |
| attached following page of this paper.   |
| Remarks/Arguments begin on page 6 of this paper.                                     |
| Please note, if a box is not checked, then no corresponding amendment is being made. |